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Contents

ADVANCED	ELECTRON-	AND ION-BE	AM FABRICATION	

- 11696 05 Single camera shot Fresnel incoherent correlation holography [11696-3]
- 11696 06 **Five-dimensional imaging with a coded pinhole array** [11696-4]

METASURFACES AND METAMATERIALS

11696 0C Femtosecond laser fabrication of diffractive optics for spatial and spectral imaging at synchrotron infrared beamlines [11696-10]

NANOPLASMONICS

11696 0H **Photothermal energy conversion in plasmonic nanoantennas as a new path for the local** growth of ZnO in nanophotonic devices [11696-15]

MICRO-OPTIC/-FLUIDIC DEVICES

- 11696 0J **Two-step MEMS microfabrication via 3D direct laser lithography (Invited Paper)** [11696-17]
- 11696 0L CAD-based metrology of freeform microlens arrays, FMLAs [11696-19]

LARGE AREA FABRICATION

- 11696 0S Uniform large area super-resolved interference lithography via beam scanning [11696-26]
- 11696 OT Large area \gg 1 cm² light trapping patterns for Si solar cells [11696-27]
- 11696 0U SCIL wafer scale direct nanoimprint for nanophotonic components and fast optical quality inspection with single nm resolution [11696-28]

ADVANCED MANUFACTURING USING DMD OR SLM: JOINT SESSION WITH 11696/11698

11696 0X Digital printing of hydrogel based diffractive optical elements [11696-31]

POSTER SESSION

- 11696 15 **RIE fabrication method of ARS for plastic lens** [11696-39]
- 11696 16 Localized surface plasmon resonance in refractory metamaterials [11696-40]